



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of )  
Koichiro TANAKA )  
Japanese Priority Application 2000-024615 ) Attn: Applications  
Japanese Priority Date: February 2, 2000 ) Branch  
For: BEAM HOMOGENIZER, LASER )  
IRRADIATION APPARATUS, )  
SEMICONDUCTOR DEVICE, AND )  
METHOD OF FABRICATING THE )  
SEMICONDUCTOR DEVICE ) Date: February 1, 2001

#3

IOS  
RAB209  
7/1/01

INFORMATION DISCLOSURE STATEMENT  
AND NOTIFICATION OF RELATED APPLICATION

Honorable Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application.

At least some of the references listed on the attached Form PTO-1449 are discussed in the specification of the subject application.

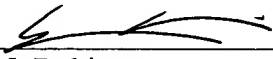
U.S. Patent Nos. 5,643,826 and 5,923,962 are listed in the patent family of Japanese Patent Application Laid-Open No. 07-130652.

The attention of the Examiner is directed to related application Serial No. 09/741,026.

Copies of the references are submitted herewith in accordance with 37 C.F.R.

1.98(a).

Respectfully submitted,



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